

FIG. 1A

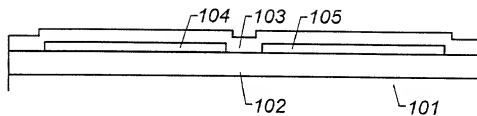


FIG. 1B

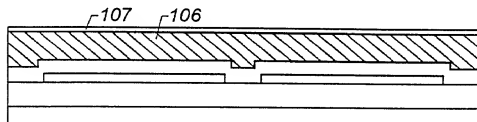


FIG. 1C

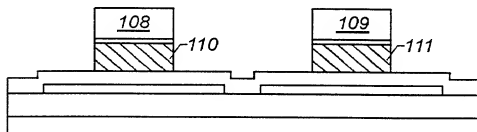


FIG. 1D

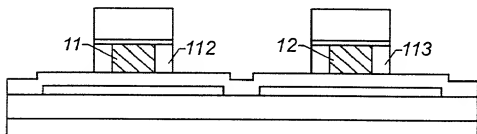


FIG. 1E

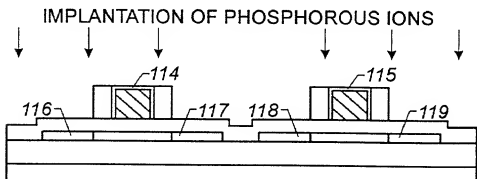


FIG. 2A

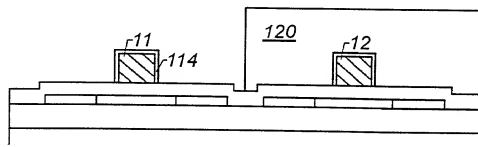


FIG. 2B

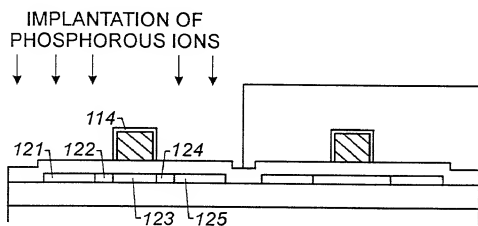


FIG. 2C

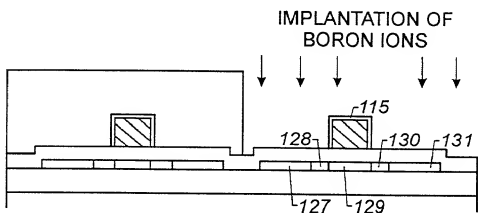


FIG. 2D

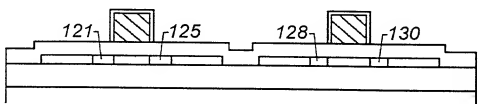


FIG. 3A

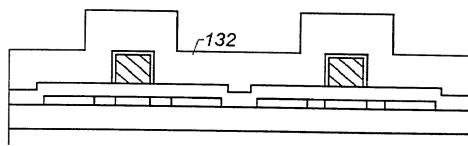
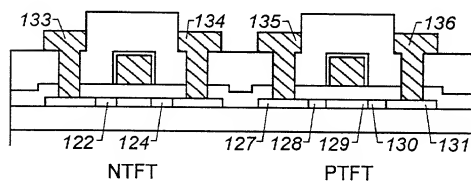


FIG. 3B



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FIG. 4A
(PRIOR ART)

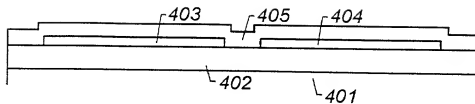


FIG. 4B
(PRIOR ART)

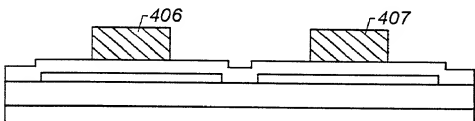


FIG. 4C
(PRIOR ART)

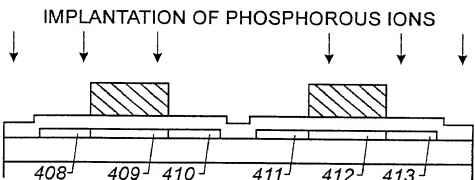
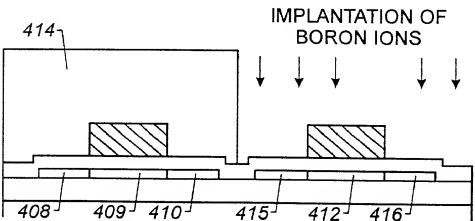


FIG. 4D
(PRIOR ART)



IMPLANTATION OF PHOSPHOROUS IONS

FIG. 5A

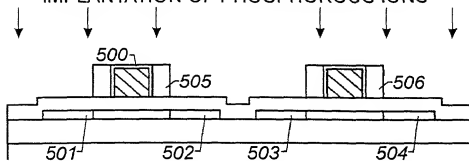


FIG. 5B

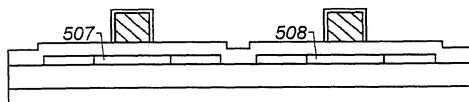
IMPLANTATION OF
BORON IONS

FIG. 5C

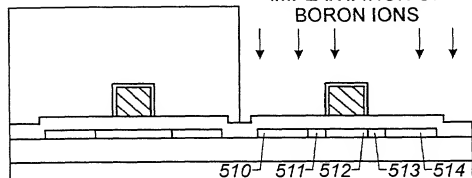
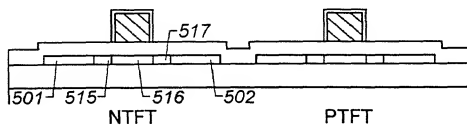


FIG. 5D



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FIG. 6A

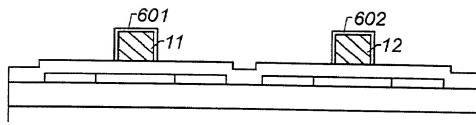


FIG. 6B

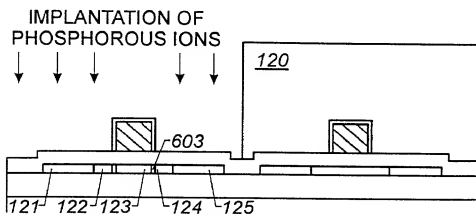


FIG. 6C

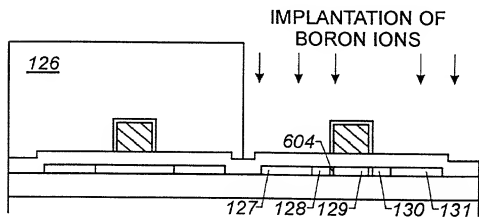
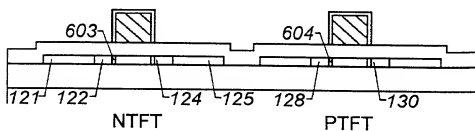
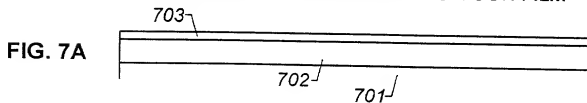


FIG. 6D

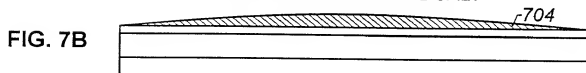


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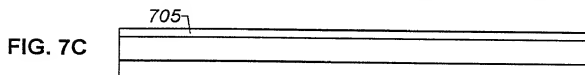
FORMATION OF AMORPHOUS SILICON FILM



FORMATION OF WATER FILM CONTAINING NICKEL SALT



HEATING PROCESS FOR CRYSTALLIZATION



HEATING PROCESS IN ATMOSPHERE CONTAINING HALOGEN ELEMENT

